

AMENDMENTS TO THE SPECIFICATION

Please replace the ABSTRACT on page 21 with the following amended paragraph:

A microelectromechanical systems (MEMS) element~~[[,]]~~ and a MEMS optical switch ~~and~~
5 ~~MEMS fabrication method~~ are described. The MEMS element comprises a crystalline
and moveable element is moveably attached to the substrate. The moveable element
includes a perpendicular portion oriented substantially perpendicular to a plane of the
substrate. The crystal structure of the perpendicular portion and substrate are
substantially similar. The moveable element ~~moveable~~ is ~~moveably attached to the~~
10 ~~substrate for~~ capable of motion substantially constrained to a plane oriented substantially
perpendicular to a plane of the substrate. In at least one position, a part of a
perpendicular portion of the moveable element projects beyond a surface of the substrate.
The moveable element may be retained in place by a latch. ~~The perpendicular portion~~
~~may be formed substantially perpendicular portion to the substrate.~~ An array of such
15 structures can be implemented to work as an optical switch. The optical switch may
comprise a crystalline substrate and one or more moveable elements moveably attached
to the substrate. ~~The MEMS elements may be fabricated by providing a substrate;~~
~~forming one or more trenches in the substrate to define a perpendicular portion of a~~
~~element; and moveably attaching the moveable element to a first surface of the substrate;~~
20 ~~removing a portion of the substrate such that at least a part of the perpendicular portion~~
~~projects beyond a second surface of the substrate.~~ The various embodiments provide for
a robust and reliable MEMS elements that may be simply fabricated and densely packed.